Table I. $E^{m}_{pair} \approx (E^{a}_{pair})$, E^{bLL}_{pair}, E^{b}_{pair}, and E^{D}_{imp} in eV, and f^{I}_{imp}. $E^{f}_{V} = 4.24$ eV [5]

Impurity-vacancy pair				Impurity diffusion		
	$E^{m}_{pair} \approx (E^{a}_{pair})$	E^{bLL}_{pair}	E^{b}_{pair}		E^{D}_{imp}	f^{I}_{imp}
(PV)	0.93[1] (0.94[3])	1.04[3]	1.87[5]	P	3.30[4]	0.6 – 0.8 [7] 0.86 – 0.96 [8,9]
(AsV)	1.07[2] (1.07[3])	1.23[3]	1.87[5]	As	3.44[4]	0.6 [7]
(SbV)	1.29[2] (1.28[3])	1.44[3]	1.88[5]	Sb	3.65[4]	0.015 [10]
(BiV)	(1.46[3])	1.64[3]	1.85[5]	Bi	3.85[4]	

4. Interstitialcy Mechanism of Impurity Diffusion

Extrinsic stacking faults are generated and the diffusion of P and As is enhanced by the oxidation of the Si specimen. Therefore, it has been proposed [6] that both P and As diffuse by the dual mechanism of vacancy and interstitialcy (I).

The fractions of the interstitialcy component in the diffusion of P (f^{I}_{P}) [7] [8,9], of As (f^{I}_{As}) [7], and of Sb (f^{I}_{Sb}) [10] are shown in Table I. *Statement 2:* "Based on these, it has been concluded [7-9] that the interstitialcy mechanism is dominant in P and As diffusion. "

5. Conclusion

Statement 1 in §3 and *Statement 2* in §4 are inconsistent. Currently, little is known about P-I and As-I pairs. Therefore, by applying Watkins' model to the interstitialcy mechanism, $E^{m}_{(PV)^0} + E^{f}_{V} \approx E^{m}_{(PI)^0} + E^{f}_{I}$ and $E^{m}_{(AsV)^0} + E^{f}_{V} \approx E^{m}_{(AsI)^0} + E^{f}_{I}$ can be obtained from eq. (1), where $E^{m}_{(PI)^0}$ and $E^{m}_{(AsI)^0}$ are the migration energies of P-I and As-I pairs, and E^{f}_{I} is the formation energy of the self-interstitial.

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